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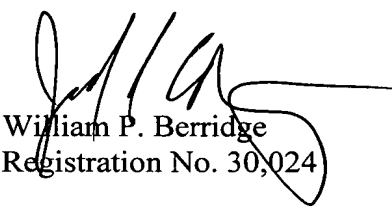
--33. The method for producing a silicon single crystal wafer according to Claim 30,
wherein the heat treatment is performed by using a rapid thermal annealer.--

REMARKS

Claims 13-33 are pending. By this Preliminary Amendment, claims 1-12 are
cancelled without prejudice to or disclaimer of the subject matter contained therein and
claims 13 - 33 are added.

Prompt and favorable examination on the merits is respectfully requested.

Respectfully submitted,


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